

## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)

11675.114.1

Application Number

09/579,402

Applicant(s)

Kei-Yu Ko

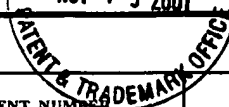
Filing Date

May 25, 2000

Group Art Unit

1765

NOV 15 2001



## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
66	1	5,821,594	10/13/98	Kasai	257	410	02/25/97
66	2	5,747,369	05/05/98	Kantimahanti et al.	438	241	01/13/97
66	3	5,422,308	06/06/95	Nicholls et al.	437	192	12/06/93
66	4	5,037,777	08/06/91	Mele et al.	437	195	07/02/90

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
66	5	04-345,054	12/01/92	JAPAN			✓	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

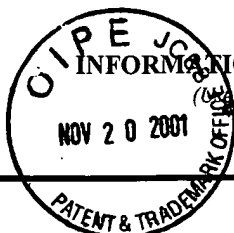

EXAMINER

DATE CONSIDERED

2/20/02

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EL	1.	6,271,542	8/2001	Emma, et al.	257	67	
EL	2.	6,242,759	6/2001	Yamazaki, et al.	257	69	
EL	3.	5,321,286	6/1994	Koyama, et al.	257	315	
EL	4.	4,489,478	12/1984	Sakurai			
EL	5.	4,472,729	9/1984	Shibata, et al.			
EL	6.	4,381,201	4/1983	Sakurai			

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	ABSTRACT Translation	
							YES	NO
EL	7.	5-335482	12/1993	Japan			✓	
EL	8.	4-360570	12/1992	Japan			✓	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


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*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		NONE					

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	ABSTRACT Translation	
							YES	NO
EL	1	56-114,355	9-8-81	Japan - Yoji			X	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

CL	1	"Mechanisms of High PSG/Silicon Dioxide Selective Etching In a Highly Polymerized Fluorocarbon Plasma"; Jpn. J. Appl. Phys. Part I; (1991); I Kegami et al., pp. 1556-1561; 30(7).

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